Linking the challenges of materials technology with the opportunities in materials research - an academic perspective

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Global R&D Trends – Implications for Materials Science

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One R&D trend in materials science – in mechanical behavior

In addition to the long established problems in the discipline of structural materials: Stiffer, Stronger, Tougher, Lighter…

We have now added: Smaller

• First motivated by needs from outside the discipline: microelectronics and functional materials

• Has led to new techniques and ideas that now benefit a broad spectrum of science and technology

* I will call this a trend *

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Mechanical behavior problems in microelectronics ~ 1983

Craig Barrett, Intel

David Barnett, Stanford
Bill Nix, Stanford

Consulting about mechanical reliability in metal interconnects – metal cracking

Created need to understand stresses and mechanical properties of thin films – need for new techniques and concepts
Hardness measurement at penetration depths as small as 20 nm

By J. B. Pethica†, R. Hutchings and W. C. Oliver‡
Brown Boveri Research Center, CH-5405 Baden, Switzerland

[Received 18 April 1983 and accepted 1 May 1983]
Oliver & Pharr Method - 1992

An improved technique for determining hardness and elastic modulus using load and displacement sensing indentation experiments


W. C. Oliver
Metals and Ceramics Division, Oak Ridge National Laboratory, Oak Ridge, Tennessee 37831-6116

G. M. Pharr
Department of Materials Science, Rice University, P.O. Box 1982, Houston, Texas 77251

Established the methodology for determining mechanical properties by nanoindentation

Google Scholar: 10,023 citations!

Most in field of Materials Science – by far!
Application to Low-k Dielectric Films

Nanonindentation compliant films

W.C. Oliver & G.M. Pharr; MRS Bulletin (2010)

Figure 8. Nanoindentation measurement of the elastic modulus of layered structures used for integrated circuits (ICs) in the semiconductor industry. The results illustrate the utility of the continuous stiffness measurement technique (CSM), which allows continuous measurement of hardness and elastic modulus as the indenter penetrates the layers. The rapid increase in elastic modulus at small depths for the blue curve in comparison to the red curve indicates that the 100nm SiON layer is much stiffer than the underlying polymer.

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Application to Biology

Nanoindentation of plaques and hardening of the arteries


Figure 10. Nanoindentation load–displacement behavior of atherosclerotic plaques that cause hardening of the arteries. The series of curves shows how the elastic modulus of the plaques increases by nearly three orders of magnitude in the various stages of development. As the plaque becomes fully calcified in the later stages, it becomes hard and brittle, leading to serious medical problems when it breaks off and moves through the blood system. The negative loads observed during unloading indicate that the indenter had adhered to the surface and had to be pulled off.
MEMS Display Technology (QUALCOMM)

Flat, Deformable Mirrors as Pixels for Electronic Readers

Residual stresses and mechanical properties of the glass films are crucial

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Nanoindentation of a high quality glass film on Si (part of mirror-pixel structure)

Continuous stiffness:
Displacement amplitude=+/- 3nm  
Frequency: 45 Hz

Film thickness=2000 nm
Hardness and modulus of a high quality glass film on Si – substrate effect

Continuous stiffness:
Displacement amplitude=+/- 3nm
Frequency: 45 Hz

Film thickness=2000 nm
Modulus of Si substrate is ~160 GPa
Poisson’s Ratio=0.18

This characterization capability did not exist before 1983

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Another newly developed technique based on an Intel-Stanford connection

Measurement and Interpretation of Stress in Aluminum-Based Metallization as a Function of Thermal History

PAUL A. FLINN, DONALD S. GARDNER, MEMBER, IEEE, AND WILLIAM D. NIX

Laser Scanning Technique for Measuring Substrate Curvature

Motion of Reflected Beam Indicates Substrate Curvature
Substrate curvature method for measuring elastic and plastic properties of thin films

Technique did not exist before the mid-1980s – led to new wave of science on the strength and plasticity of thin film materials

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Interest in stress measurement led to new in-situ techniques

J.A. Floro, E. Chason and S.R. Lee,
MRS Symposium, Fall 1995
Stress Evolution in Deposited Thin Films

V. Ramaswamy & B.M. Clemens, (2001)

A new line of research on the origins of stresses in thin films


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What are the lessons learned?

• Useful to consider problems outside your own discipline or specialty (microelectronics, functional materials)

• Useful to look for new techniques or methods that can be used to address the new problems
  - Nanoindentation
  - Substrate curvature techniques

• Connecting the new techniques to the new problems leads to new lines of research that both contribute to the solution of important problems and advance the discipline (mechanical behavior)
Subra Suresh’s work on Malaria

Problem: Malaria induced by P. falciparum in red blood cells; most widespread parasitic disease in humans


From research on metal fatigue and thin film mechanical properties to research on malaria!

Huge change in elastic rigidity
A new problem in the field of lithium ion batteries - decrepitation

Decrepitation Model For Capacity Loss During Cycling of Alloys in Rechargeable Electrochemical Systems

R.A. Huggins* and W.D. Nix**
Ionics, Vol. 6, 57-63 (2000)

Smaller particles resist fracture – understood in terms of fracture mechanics

But problem did not attract attention until….

K. Rhodes et al. Journal ECS

Nanowire electrodes synthesized!

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The decrepitation problem and a nanowire solution

Si anode in Li\(^+\) battery

Silicon is a promising anodic material

Experiences huge volume expansion and decrepitation

Nanowire electrodes more tolerant


Is there a critical size?

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Modeling fracture using the electrochemical shock – thermal shock analogy

Lithiation Delithiation

Surface cracking

Axis of symmetry

Interior cracking

Li+ insertion

Axis of symmetry

Li+ extraction

I. Ryu et. al., JMPS, 2011

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But surface cracking of crystalline Si is observed during lithiation!
Core-shell lithiation of Si NWs

Two phase core-shell


Interface reaction controlled

\[ \sigma_\theta = \sigma_Y (1 - \ln(b/r)) \]

Tension at surface

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In-situ TEM of Si nanoparticles during lithiation

M.T. McDowell, I. Ryu, S. W. Lee et al., Advanced Materials, 2012

Fracture at surface

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Size dependence of fracture

$<111>$ Si nanopillars

S. W. Lee et al., PNAS, 2012

Smaller size and slow reaction prevent fracture

$\sim 300 \text{ nm}$ is critical diameter of fracture

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Lithiation of an amorphous Si nanoparticle

M.T. McDowell et al, Nano Letters (2013)

No Fracture!

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Lithiation of amorphous Si nanopillars

No fracture observed for diameters up to a few micrometers

L.A. Berla et al., in preparation, 2013

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What are the lessons learned?

• Useful to consider problems outside your own discipline or specialty (electrochemistry and batteries)

• Useful to look for new techniques or methods that can be used to address the new problems

  Nanowires
  Nanopillars

• Connecting the new techniques to the new problems leads to new lines of research that both contribute to the solution of important problems and advance the discipline (mechanical behavior)
Conclusions

• Useful to consider problems outside your own discipline or specialty – **beware of learning more and more about less and less**

• Useful to look for new techniques or methods that can be used to address the new problems – **they need not be “invented here”**

• Connecting the new techniques to the new problems leads to new lines of research that both contribute to the solution of important problems and advance the discipline

• This style of research has become a trend in recent decades

*W.D. Nix, Wadsworth Symposium*
Thank you for your interest and attention

and congratulations to Jeff